

2.674 Introduction to Microfluidics II

- Droplets and Surface

Sang-Gook Kim

Understanding diffusion

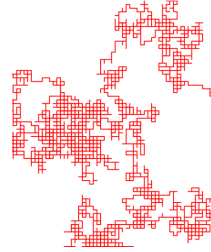
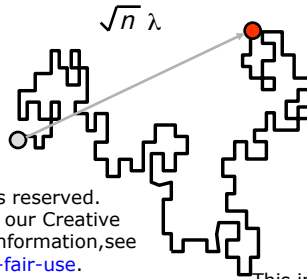
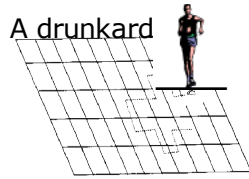
- Macroscopic diffusion 'results' from random motion of individual molecules

$$\overline{x^2} = 2 \cdot D \cdot t$$

- When a large number of molecules is observed, diffusion seems to be a smooth, continuous process with no indication of underlying randomness

Observe random motion of microspheres in the lab!

Random walk -2D, 3D



© sources unknown. All rights reserved.
 This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

This image is in the public domain.

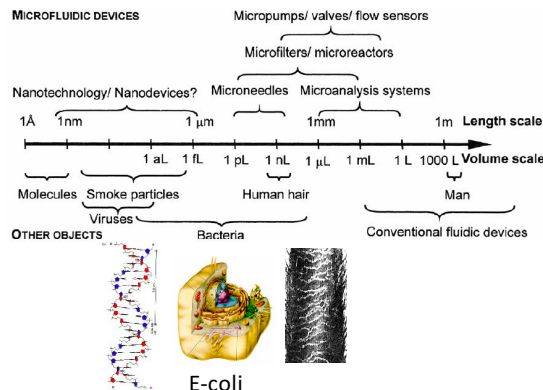
This image has been removed due to copyright restrictions. Please see https://commons.wikimedia.org/wiki/File:Wiener_process_3d.png.

This image has been removed due to copyright restrictions. Please see <https://ca.wikipedia.org/wiki/fitxer:Brownianmotion5particles150frame.gif>.

Sullivan, t. jat English Wikipedia.

Scales of Fluidics

Microfluidic devices - dimensions



© Karen Cheung, UBC ECE. All rights reserved.
 This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

1 molecule in 1 mL = 1.6×10^{-18} M
 1 molecule in 1 nL = 1.6×10^{-15} M
 1 molecule in 1 pL = 1.6×10^{-12} M

Credit: Dr. Karen Cheung, UBC ECE

Droplets

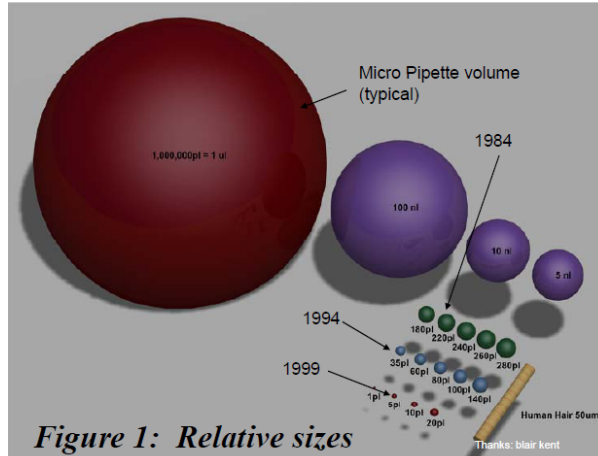


Figure 1: Relative sizes

© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

HP POEM Thermal Ink Jet System

The diagram shows the HP POEM Thermal Ink Jet System. On the left, a three-step diagram illustrates the nozzle operation: 1. Ink is drawn into the nozzle. 2. A droplet is formed at the nozzle tip. 3. The droplet is ejected from the nozzle. On the right, a photograph of the machine is shown with several callout boxes: 'Alignment Machine Vision System', 'Precision Motion Stages (repeatability +/- 1µm)', 'Thermal Ink Jet Pico-liter System (TIPS) Controller', and 'Thermally Controlled Vacuum Platen'. Below the photograph, a list of features is provided: 'Droplet sizes: 200 - 0.5pl' and 'Disposable nozzles with 0.5ml reservoir'. The text 'Bathurst, MIT, 2012' is at the bottom right.

- Droplet sizes: 200 - 0.5pl
- Disposable nozzles with 0.5ml reservoir

Bathurst, MIT, 2012

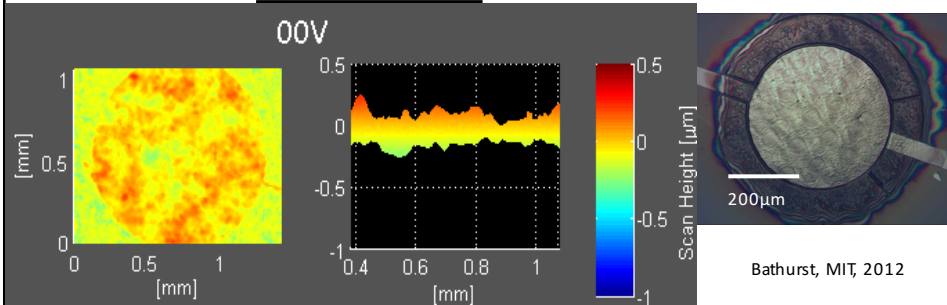
© Bathurst at MIT. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Printed PZT Devices

- To confirm the quality of printed PZT capacitors and MEMS devices were fabricated and tested
- A Standard PZT device structure was used:
Si Substrate / 200nm SiO₂ / 20nm Ti / 200nm Pt / PZT 300-700nm

Ferroelectric Test Capacitors

Released MEMS Structures



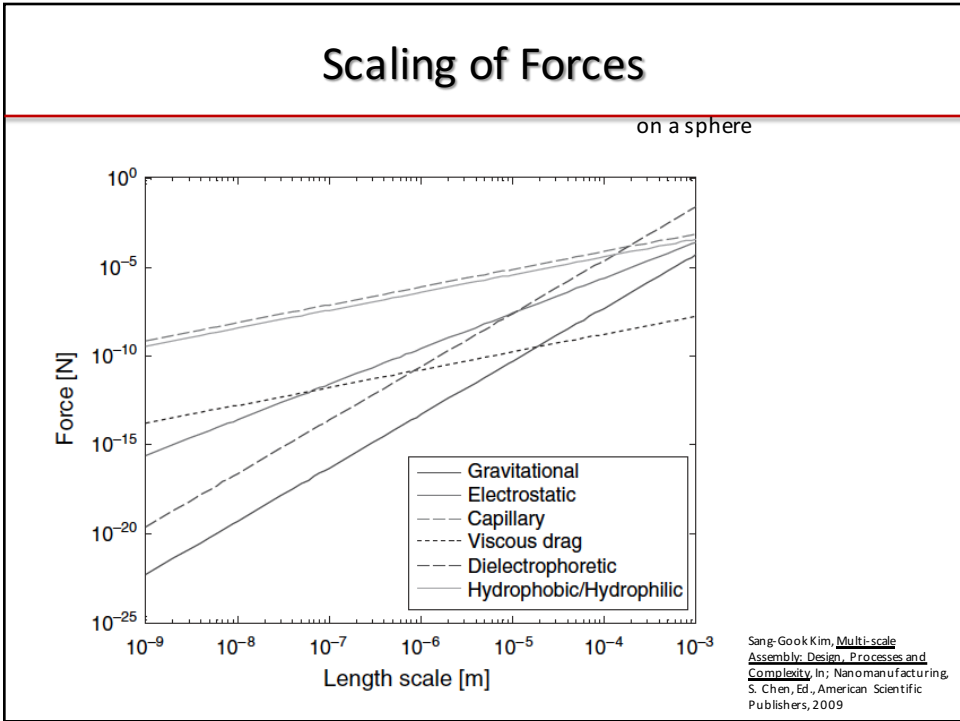
Bathurst, MIT, 2012

© Bathurst at MIT. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Scaling of Forces

Types of forces	Equation
Capillary force	$F_C = 4\pi R\gamma \cos \theta$
Hydrophobic/hydrophilic	$F_H \approx \frac{2\gamma(1 - \cos \theta)(\pi R^2)}{d}$
Viscous drag force	$F_d = 6\pi\eta(R)v$
Electrostatic force	$F_{ES} = \frac{1}{4\pi\epsilon_0\epsilon_m} \frac{\{q_1(2\pi R_1^2)\}\{q_2(2\pi R_2^2)\}}{r^2}$
Dielectrophoretic	$F_{DEP} = \frac{3}{2} \left(\frac{4}{3}\pi R^3 \right) \epsilon_m \left(\frac{\epsilon_o - \epsilon_m}{\epsilon_o + 2\epsilon_m} \right) \nabla \bar{E} ^2$ $\approx \frac{3}{2} \left(\frac{4}{3}\pi R^3 \right) \epsilon_m \left(\frac{\epsilon_o - \epsilon_m}{\epsilon_o + 2\epsilon_m} \right) \frac{r^2 V^2}{d^5}$
Gravitational force	$F_G = g\rho \left(\frac{4}{3}\pi R^3 \right)$
Electrophoretic	$F_{EP} = q(4\pi R^2) \bar{E} $
Magnetic	$F_M = \frac{\mu_0\mu_m}{4\pi} \frac{q_{M1}q_{M2}}{r^2}$ $= \frac{\mu_0\mu_m}{2} (\pi R^2) M^2$

Sang-Gook Kim, *Multi-scale Assembly, Design, Processes and Complexity*, in: Nanomanufacturing, S. Chen, Ed., American Scientific Publishers, 2009



Surface Tension

This image has been removed due to copyright restrictions. Please see <http://www.damtp.cam.ac.uk/user/dv211/pin2.jpg>.

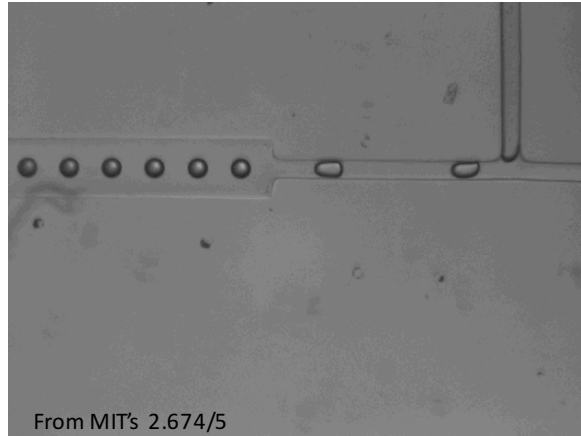
γ - Force per unit length of interface

Denotes the energy required to create an interface

This image has been removed due to copyright restrictions. Please see http://jncc.defra.gov.uk/images/sem_lotus-w eb_v_Variation_2.jpg.

This image has been removed due to copyright restrictions. Please see https://jonahlundberg.files.wordpress.com/2011/02/water_drop_lets_sc.jpg?w=590.

Droplet formation - A balance of surface tension forces and viscous forces



From MIT's 2.674/5

Emulsion and Surfactant

- Mixture of Immiscible liquids
- Amphiphilic Surfactant
- Water soluble or oil soluble

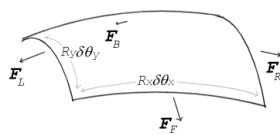
This image has been removed due to copyright restrictions.
Please see http://www.horiba.com/uploads/pics/Micelle_Concentration.JPG.

Droplet formation

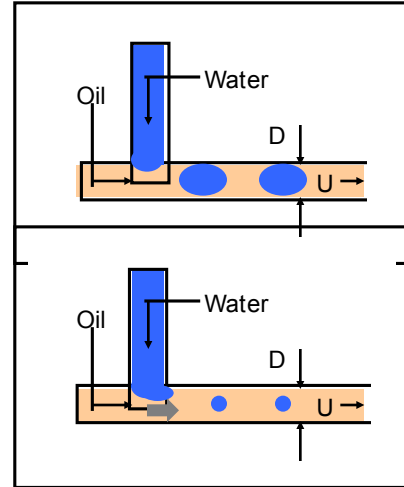
- Dynamic instability between surface tension and shear stress causes plug formation

- Laplace pressure

$$\Delta P = \gamma \left(\frac{1}{R_x} + \frac{1}{R_y} \right)$$



This image has been removed due to copyright restrictions. Please see the images at http://soapbubble.wikia.com/wiki/Giant_Bubbles.



Two phase flow

- Surface tension favors large droplet

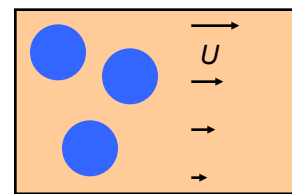
Laplace pressure:
$$P_L = \frac{2\gamma}{r}$$

- Shear stress tends to break up droplet

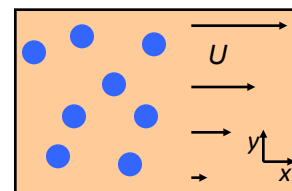
Shear stress:
$$\tau = \mu \frac{dU}{dy}$$

- Droplet size:

$$P_L \approx \tau \Rightarrow r \sim \frac{2\gamma}{\mu(dU/dy)}$$



Small shear stress



Large shear stress

Capillary number

- Viscous shear stress (N/m²)

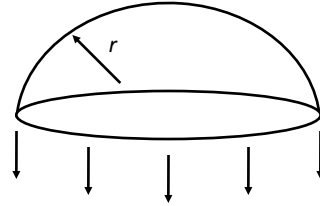
$$\tau_{viscous} \sim \mu \frac{U}{D}$$

- Laplace pressure (N/m²)

$$P_{Laplace} \sim \frac{2\gamma}{r}$$

- Ratio of viscous force to surface tension force:

$$Ca \sim \frac{\tau_{viscous}}{P_{Laplace}} \sim \frac{\mu U/D}{2\gamma/D} \sim \frac{\mu U}{\gamma}$$



Droplet formation

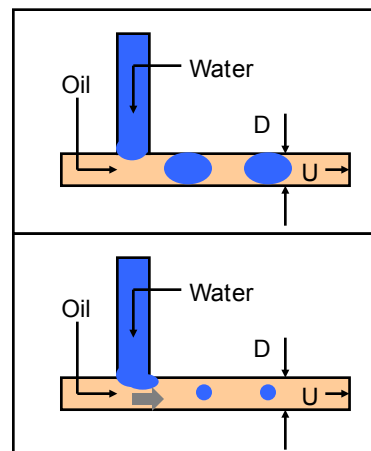
- Dynamic instability between surface tension and shear stress causes plug formation

$$Ca = \frac{U\mu}{\gamma}$$

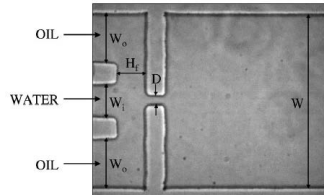
$$\frac{dU}{dy} \sim \frac{U}{D} \Rightarrow r \sim \frac{2\gamma}{\mu(dU/dy)} = \frac{2\gamma D}{\mu U}$$

$$r \sim \frac{2D}{Ca}$$

- **Small Ca**: Droplet size governed by channel geometry
- **Large Ca**: Droplets break up

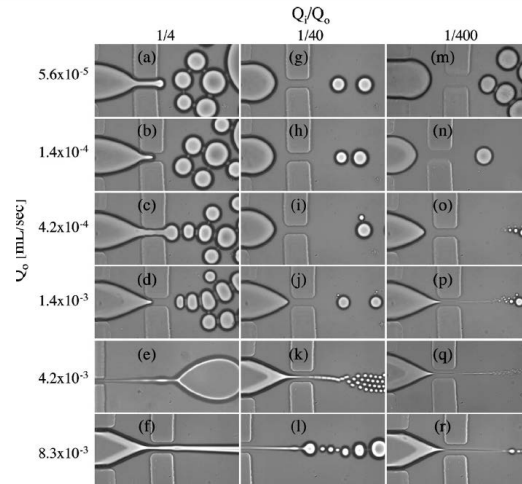


Droplet formation by flow focusing



$$Ca = \frac{U\mu}{\gamma}$$

Phase diagram of droplet formation

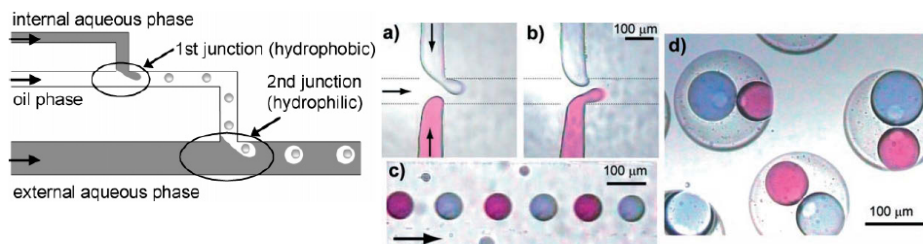


© American Physical Society. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Anna et al, Applied Physics Letters, 82, 364 (2003)

Droplet microfluidics

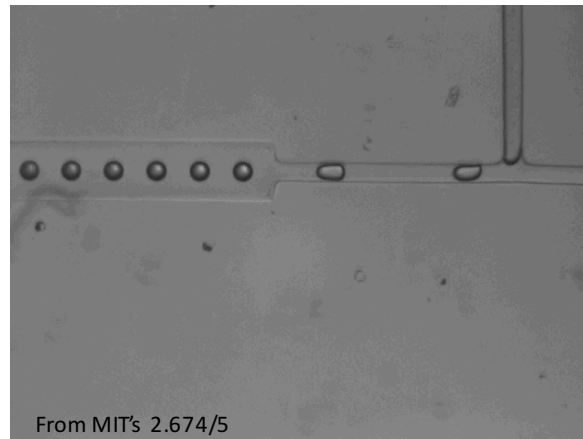
- Why use droplets?
 - Droplets can act as micro-reactors
 - Useful for emulsion and particle synthesis
 - Useful for large-scale screening of cells and molecules



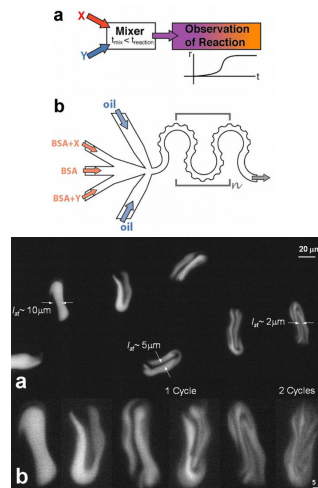
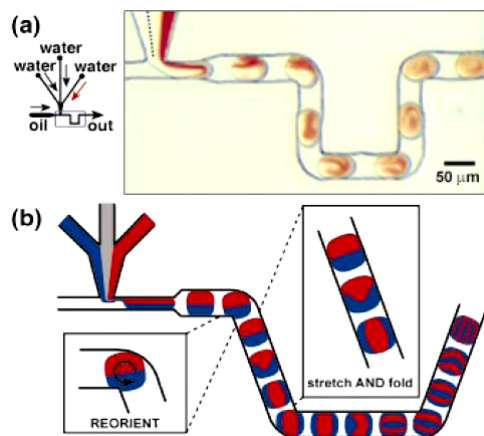
© American Chemical Society. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Okushima et al, Langmuir 20, 9905 (2004)

Droplet-Wall Interaction



Mixers employing baker's transform: Droplets

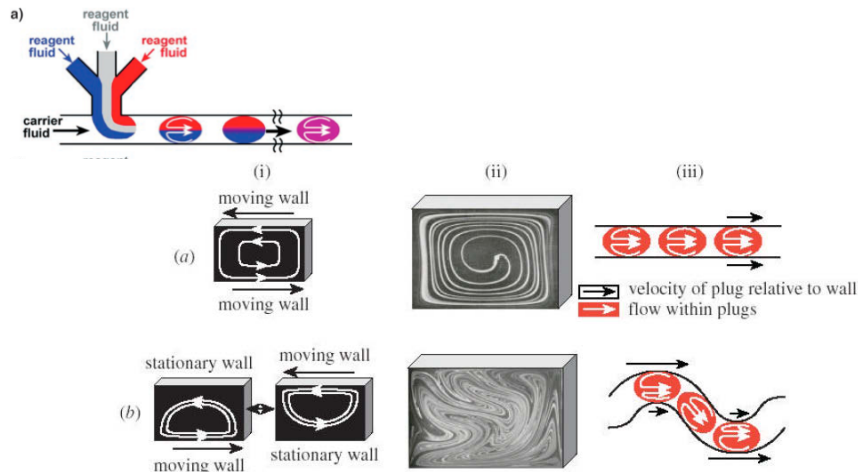


© American physical Society and American Chemical Society. All rights reserved.
This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Song et al., Applied Phys. Lett. (2003)

Liau et al., Analytical Chem. (2005)

Mixers employing blinking flow

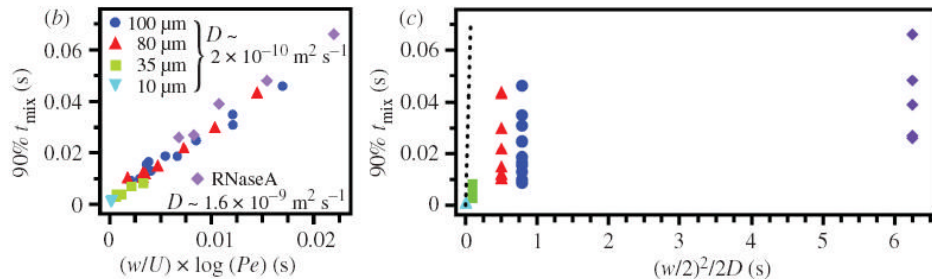
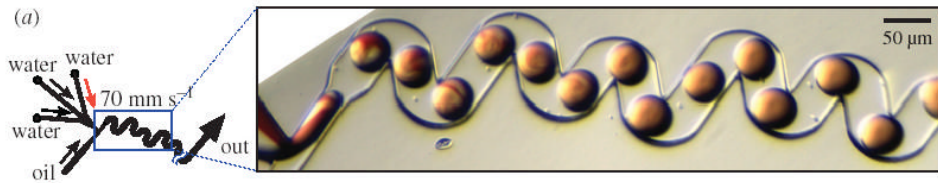


© Royal Society Publishing, Cambridge University Press, and sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Bringer et al., Philos Transact A (2004)

Ottino, The kinematics of mixing: stretching, chaos, and transport

Mixers employing blinking flow



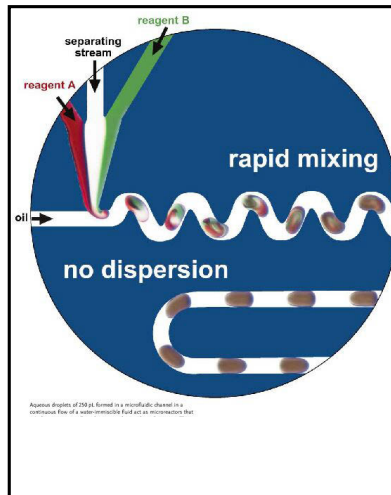
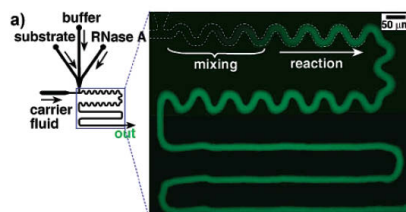
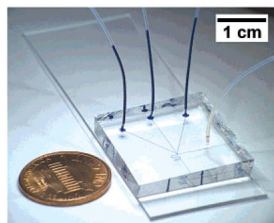
© Royal Society Publishing, Cambridge University Press, and sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Bringer et al., Philos Transact A (2004)

Ottino, The kinematics of mixing: stretching, chaos, and transport

Droplets as reactors

Measurement of fast reaction kinetics



© American Chemical Society. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Song & Ismagilov, JACS (2003)

Synthesis of particles

- Rapid mixing provides homogeneous reaction environment
- Addition of reactants within millisecond intervals- Control of reaction in time
- More homogeneous particle production

This image has been removed due to copyright restrictions. Please see Figure 5 in <http://pubs.rsc.org/en/content/articlehtml/2004/lc/b403378g>.

This image has been removed due to copyright restrictions. Please see Figure 1 in <http://pubs.rsc.org/en/content/articlehtml/2004/lc/b403378g>.

Shestopalov et. al *Lab Chip* 2004

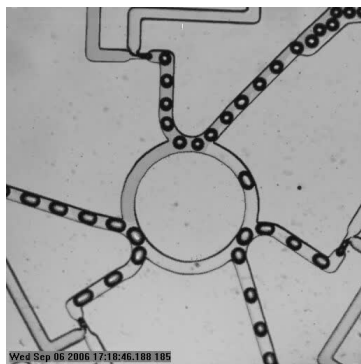
Synthesis of particles

Polymerization of droplet contents results
in nanoparticles
Use in medicine, agriculture, cosmetics

This image has been removed
due to copyright restrictions.
Please see Figure 1 in <http://pubs.rsc.org/en/content/articlehtml/2004/lc/b403378g>

This image has been removed
due to copyright restrictions.
Please see <http://ichf.pong.pl/i/m/1/214.png>.

Microfluidic logic



Ring Oscillator, Prakash
and Gershenfeld, Science
(2007)

© Science. All rights reserved. This content
is excluded from our Creative Commons
license. For more information, see
<https://ocw.mit.edu/help/faq-fair-use>.

Wetting

- Surface energy (J/m²) = Surface tension (N/m)
- Wetting occurs when work of wetting is positive.

$$W_s = \gamma_{SG} - \gamma_{SL} - \gamma_{LG} \geq 0$$

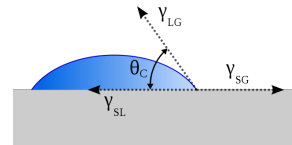
- Hydrophobic when work of wetting is negative.

$$W_s = \gamma_{SG} - \gamma_{SL} - \gamma_{LG} \leq 0$$

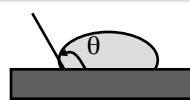
- Young's Equation

$$\gamma_{SG} = \gamma_{LG} \cos \theta + \gamma_{SL}$$

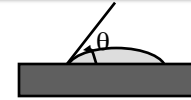
Young's Equation, Phil. Trans. Roy. Soc, 1805



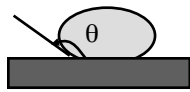
Super Hydrophobicity



Hydrophobic, $\theta > 90^\circ$

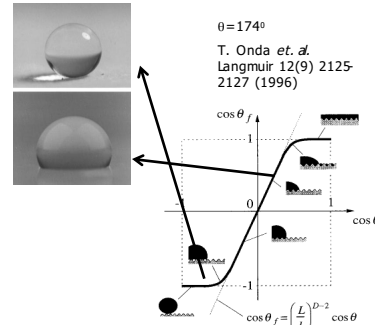


Hydrophilic, $\theta < 90^\circ$



Super hydrophobic, $\theta > 150^\circ$

- Chemical modification, coating
- Nanostructured surface

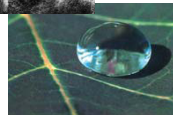
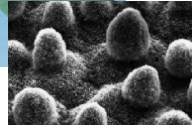


© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

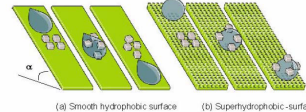
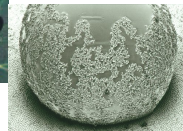
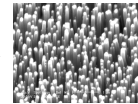
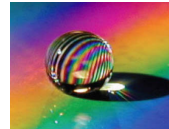
Lotus Effect



W. Barthlott and C. Neinhuis, *Planta* 202, 1 (1997)



- Some plant leaves have near 170° contact angle, and show no accumulation of dirt. (Lotus Effect)
- Superhydrophobicity by nano patterned surface
- Self-cleaning surface (no car wash?)

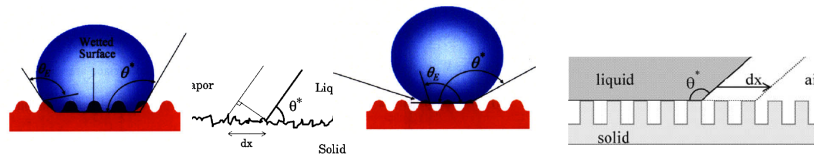


Nanotech Lecture: 'Self-Cleaning Surfaces' by Dr. Vesselin Paunov

29

© Springer Publishing Company, Vesselin Paunov, and sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Effect of surface roughness



© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Wenzel's model

- If the surface has a high free energy, roughness promotes wetting.
- If it has low free energy, roughness promotes hydrophobicity.

$$\cos \theta^* = r \cos \theta$$

$$r = \frac{\text{actual_area}}{\text{projected_area}}$$

θ^* = apparent_contact_angle

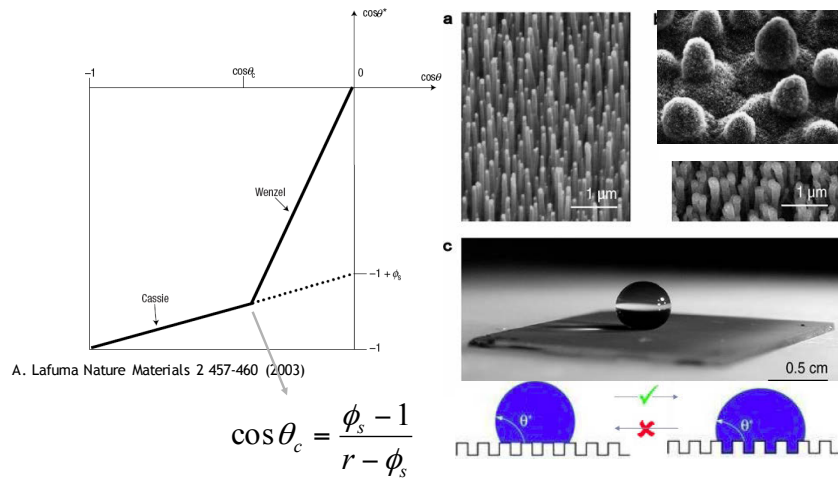
Cassie's model

- Wettability of heterogeneous (solid+air) surfaces
- Contact angle on air fraction is 180°.

$$\cos \theta^* = -1 + \phi_s (\cos \theta + 1)$$

$$\phi_s = \text{solid_fraction_surface}$$

Cassie to Wenzel transition



© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Electrowetting



© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Digital microfluidics

Electrowetting on Dielectrics (EWOD)

Droplets can be manipulated by electrowetting

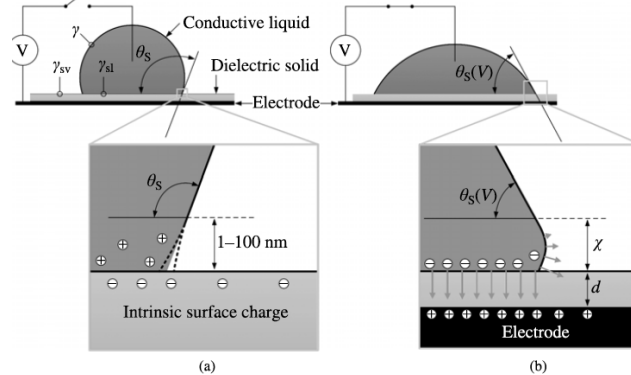
Application of voltage bias between electrodes used to manipulate droplets

Complex operations can be performed

This image has been removed due to copyright restrictions. Please see <https://mgitecetek.files.wordpress.com/2012/05/ew.jpg?w=640>.

Electrowetting

W. C. Nelson, C.-J. Kim / J. Adhesion Sci. Technol. 26 (2012) 1747–1771 1751

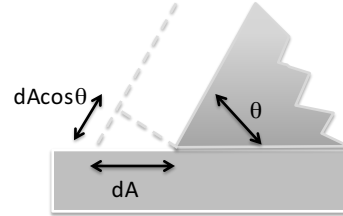


© Informa UK Limited. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

$$\frac{\text{Interfacial Force}}{\text{Length}} = C \frac{V^2}{2}$$

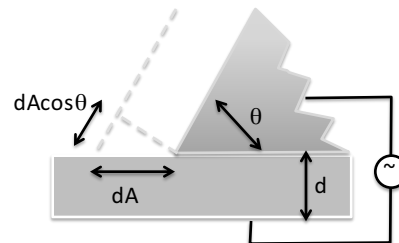
Energy Balance

$$W_s = \gamma_{SG} - \gamma_{SL} - \gamma_{LG} \geq 0$$



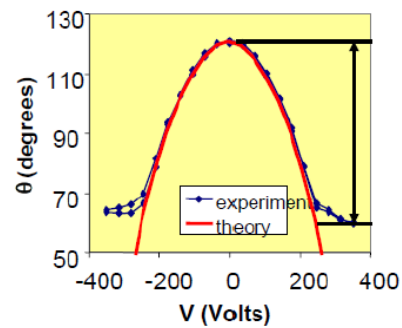
$$dW = \gamma_{LG} \cos \theta dA + \gamma_{SL} dA - \gamma_{SG} dA = 0$$

Contact Angle vs. V



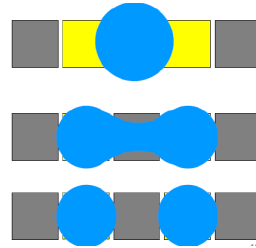
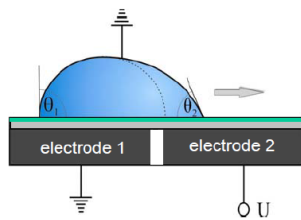
$$\cos \theta = \cos \theta_0 + \frac{1}{2} \frac{\epsilon_0 \epsilon_r}{\gamma d} V^2$$

Lippmann Young Equation



Drop Manipulation

- Merge
- Split
- Move



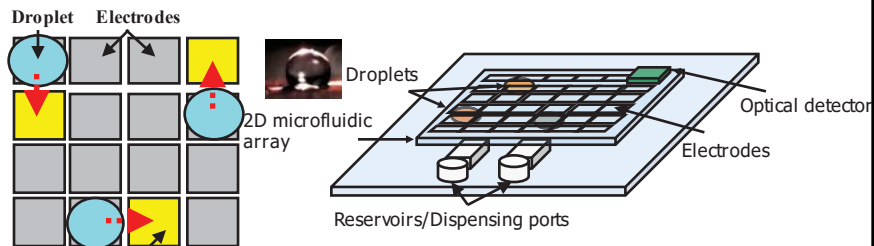
Digital microfluidics

This image has been removed due to copyright restrictions. Please see https://www.aas.org/sites/default/files/content_files/1007_STM.jpg.

This image has been removed due to copyright restrictions. Please see <https://www.technologyreview.com/s/415654/novel-chip-for-monitoring-br-east-cancer/>.

Chip for estrogen assay

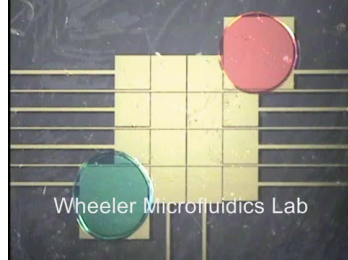
Mousa et al, Science Trans. Med. 1,1 (2009)



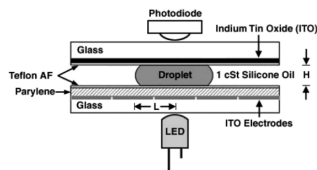
High voltage to generate an electric field

© sources unknown. All rights reserved. This content is excluded from our Creative Commons license. For more information, see <https://ocw.mit.edu/help/faq-fair-use>.

Digital microfluidics



Wheeler group, U Washington



UT Austin

© U. Washington, UT Austin, and sources unknown. All rights reserved.
 This content is excluded from our Creative Commons license. For more
 information, see <https://ocw.mit.edu/help/faq-fair-use>.

MIT OpenCourseWare
<https://ocw.mit.edu>

2.674 / 2.675 Micro/Nano Engineering Laboratory
Spring 2016

For information about citing these materials or our Terms of Use, visit: <https://ocw.mit.edu/terms>.